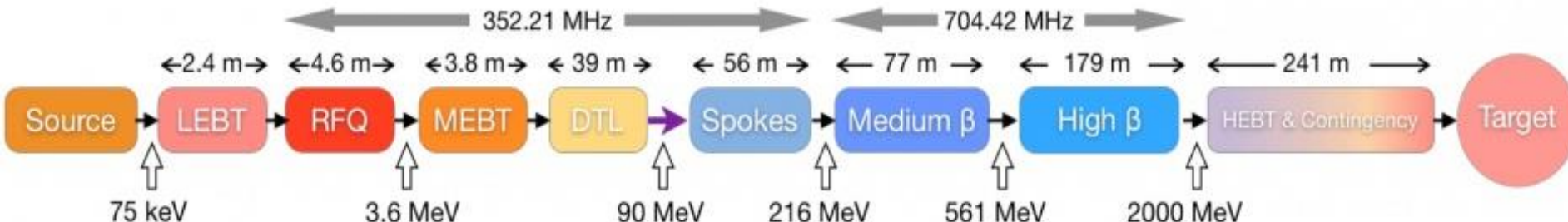


DE LA RECHERCHE À L'INDUSTRIE



ESS COUPLERS: MANUFACTURING AND CONDITIONING

Optimus+



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■ Overview of the ESS couplers for elliptical cavities

- General characteristics
- Manufacturing of the Window, Double-wall tube and Doorknob

■ Preparation of the couplers before conditioning

- Inspection at the delivery of the components
- Cleaning and assembly of the couplers on the coupling box
- Baking

■ Conditioning

- Test bench and conditioning criteria
- Results of the conditioning

■ Conclusion + comments about couplers on cryomodules

120 couplers for ESS elliptical cavities (contract with PMB: 36 medium beta (MB) whose 6 pre-series couplers for the validation of the manufacturing process + 84 high beta (HB) couplers after a quality milestone about MB couplers).

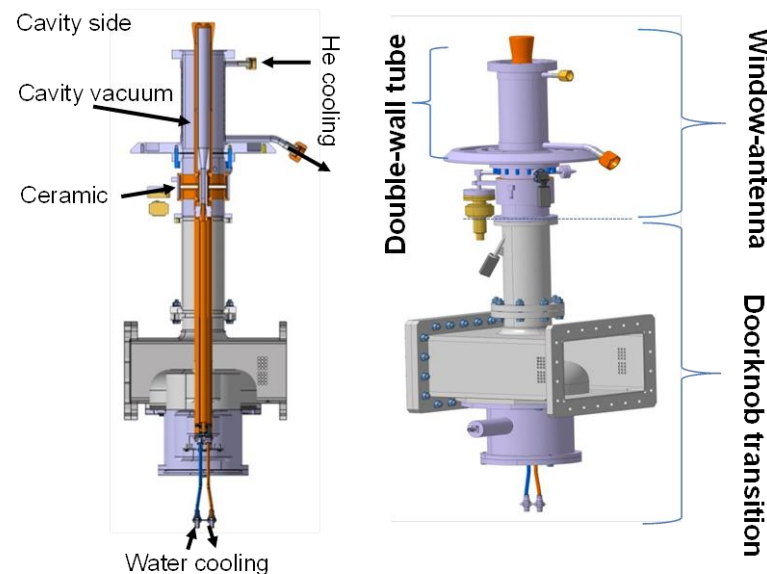
Features of the couplers

Features	Value
●RF frequency	704.42 MHz
●Repetition frequency	14 Hz
●Incident RF power	1.1 MW
●RF pulse width in full reflection (all phases)	500 μ s
●RF pulse width in travelling wave	3.6 ms
●Voltage withstand (voltage between internal conductor and external conductor)	± 10 kV

Nominal temperature	20°C
Temperature during baking	Max : 200°C for 100h
Water pressure in cooling circuit	3 bars
Water flow in cooling circuit	3 l/min
Water temperature in the antenna	from 20 to 25°C

Architecture of the couplers

- Three main parts: a single window with its antenna, a double-wall tube, a doorknob transition.
- Antenna window and doorknob transitions common to MB and HB cavities. Double-wall tube slightly different between the 2 kinds of cavities: only the tube length is modified





MANUFACTURING OF THE COUPLERS

Characteristics

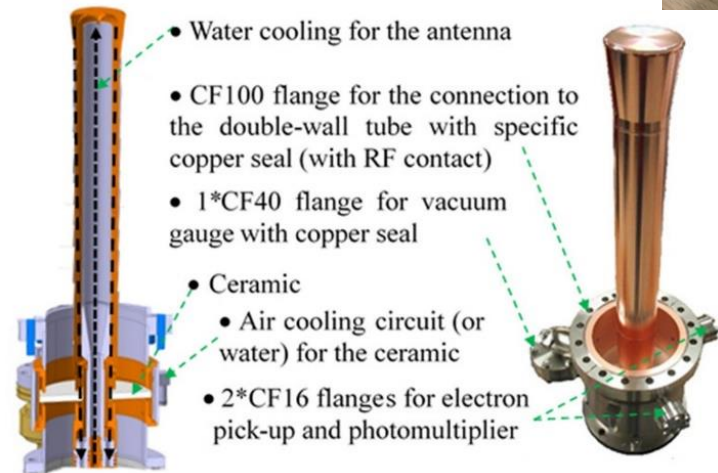
- Diagnostic equipment: Electron pick-up, view port with a photomultiplier for arc detection on the vacuum side of the ceramic, IKR070 vacuum gauge from Pfeiffer
- TiN coating on the ceramic (vacuum side) (10 nm \pm 5 nm thickness)
- Copper coating (30 μ m)
- Electropolishing of the antenna
- Electron beam welding for the antenna
- Operation steps: Brazing of the ceramic, TiN coating, EB welding

Electron pick-up



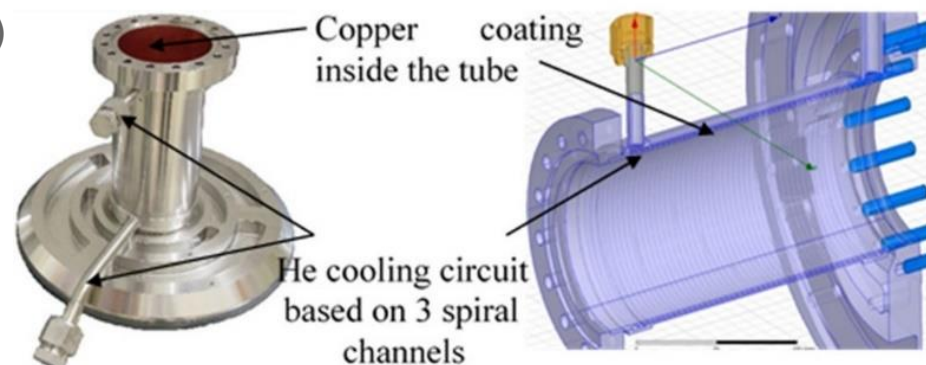
Validation during the manufacturing

- Vacuum tightness
- Water tightness
- Pressure test for the antenna cooling circuit and the ceramic cooling circuit
- Quality of the TiN coating (thickness and stoichiometric measurements on samples)
- Thickness and quality of the copper coating
- Dimensional control (antenna length, diameters of inner and outer conductors...)
- Roughness of the antenna
- Electric insulation between inner and outer conductors (>1G Ω)
- RF measurements on a window without antenna and on couplers put by pair with tubes on a coupling box



Characteristics

- Welding of the flanges
- Copper coating ($10\mu\text{m}$, $\text{RRR} \in [20;40]$)

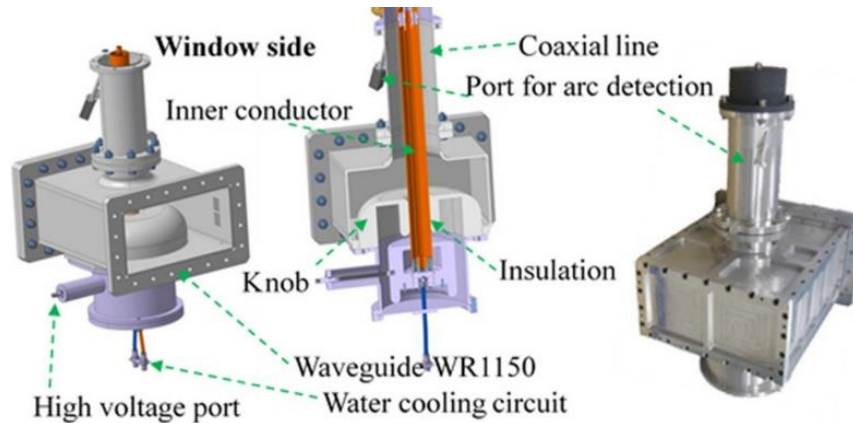


Validation during the manufacturing

- Vacuum tightness of the inner part and of the cooling circuit
- Pressure test for the cooling circuit
- Dimensional control (tube length, diameter of outer conductors...)
- RF measurements with window
- Copper layer thickness and RRR measurements on samples
- Quality of the copper layer (no cracks, no oxidation...)
- Thermal shock (comment: on cryomodules, temperature gradient from 2K (small flange) to ambient temperature (big flange))

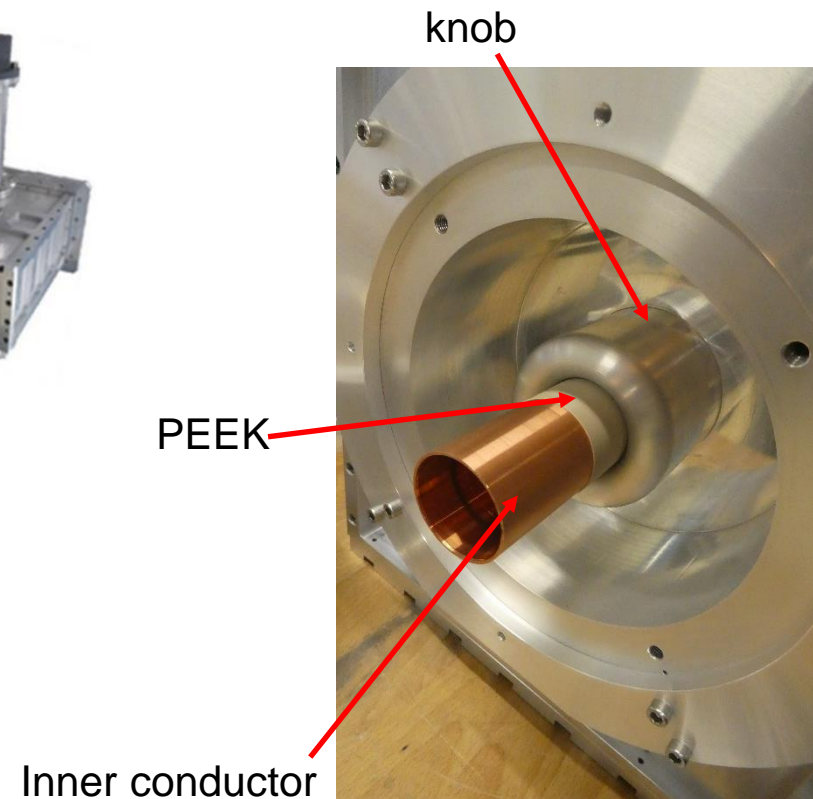
Characteristics

- Insulation obtained with a material with a dielectric constant ≈ 3.3 ($\pm 10\%$) able to provide 10kV insulation (breakdown voltage ≥ 18 kV).
- Insulation cylinder obtained from solid material and machining. No lamination, no adhesive tape, no film roll. Shrink-fitting method



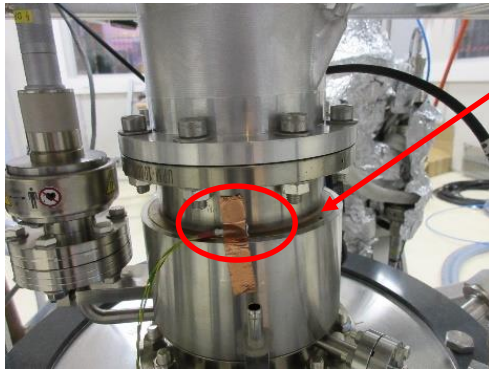
Validation during the manufacturing

- Vacuum tightness of the cooling circuit
- Pressure test for the cooling circuit
- Electric insulation test (10kV)
- Dimensional control
- RF measurements

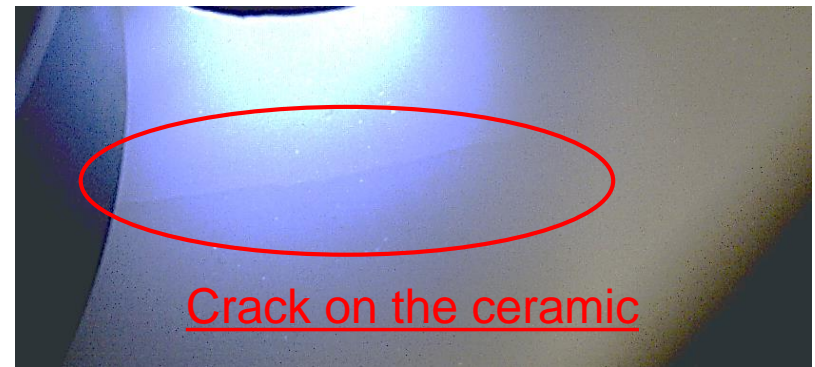


Problem with the TiN coating

- Conditioning OK for the 6 pre-series MB couplers
- For the first series MB couplers, high increase of the window temperature (+22°C instead of + 1,6°C. On the first coupler, crack on ceramic during the conditioning and loss of vacuum tightness)

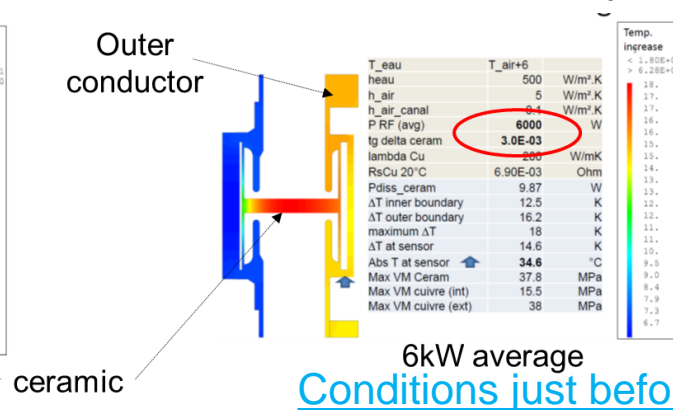
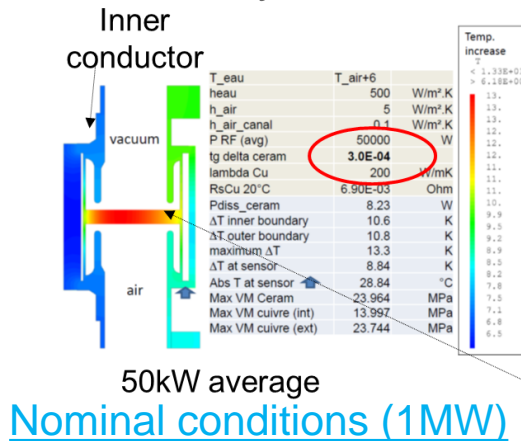


Temperature probe



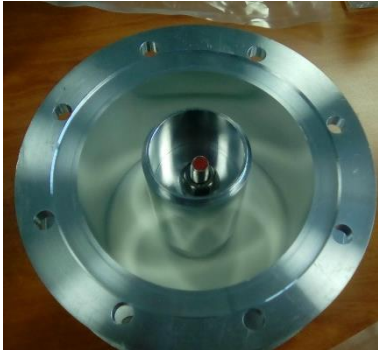
Crack on the ceramic

- Simulations performed to find the origin of the temperature increase: if the ceramic losses increase by a factor 10, we can reach the measured temperature before the crack



■ Problem with the TiN coating

- Conditioning of a window without TiN coating: no high temperature increase but lots of electrical arcs in standing waves.
- TiN coating on a ceramic put in a window mock-up, measurement of the equivalent dielectric losses at 1.8GHz in a resonant cavity: ceramic without TiN ($\epsilon_r=9.47$ and $\tan \delta=2.78 \times 10^{-4}$) and a ceramic with bad TiN ($\epsilon_r=9.44$ and $\tan \delta=2.04 \times 10^{-3}$) (measurement correlated with simulations to extract the equivalent permittivity).



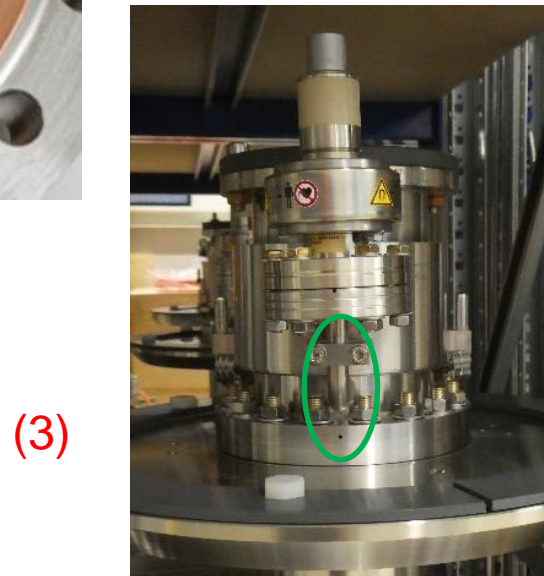
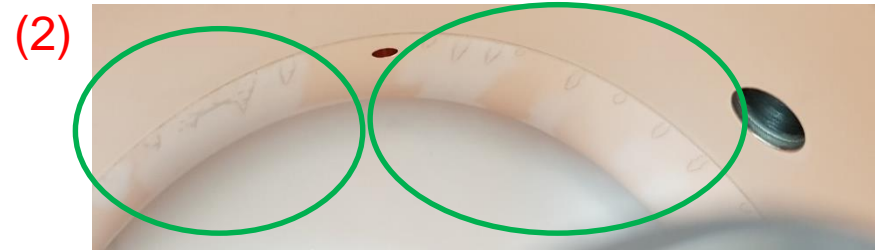
Window mock-up



Ceramic after TiN coating
(not the nominal adjustment)

- The problem of high temperatures comes from the ceramic losses due to a bad TiN thin film
- Change of the TiN coating adjustments (No improvement, impossible to find the changes between pre-series and series TiN coating).
- Finally, change of the TiN subcontractor and launch of a new qualification.
- Almost 1 year to find a correct TiN thin film.

- **Pollution of the ceramic:** Bad positioning of the ceramic protection during the electron beam welding (1)
- **Flow of the filler metal on the copper** during the brazing (2)
- **Weakness of the weld** close to the vacuum gauge flange (3) (2 windows with leak). As we can tilt the tube when we screw the gauge on the window flange, we can weaken the weld.

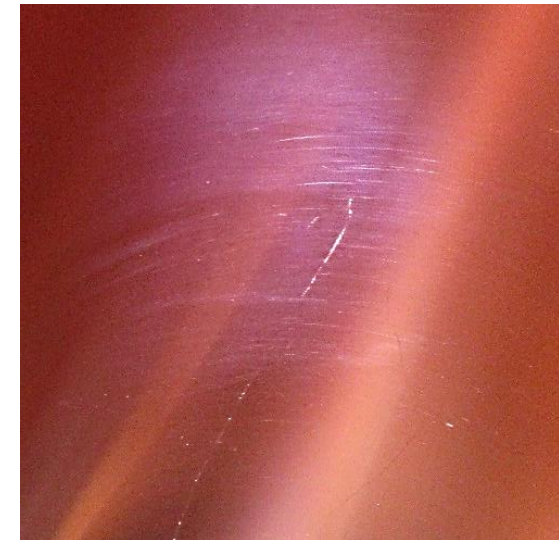


■ Copper coating:

- **Aspect:** coating is operator dependent. Last year, obligation de remove copper coat on 12 tubes (scratch, stain, mark...)

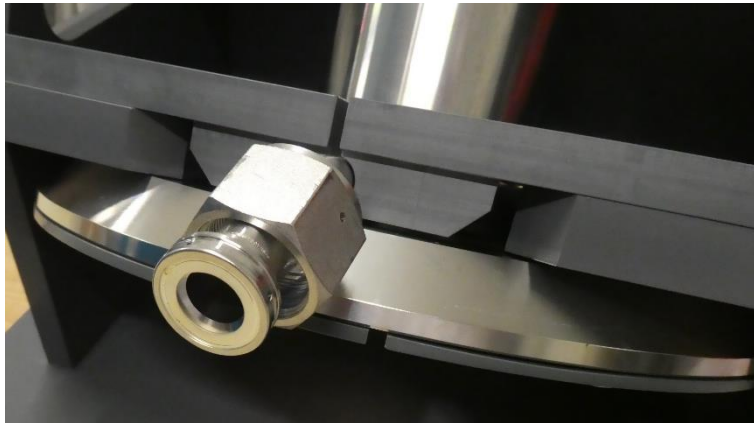


- **RRR** measured on copper coated samples: close to 100 instead of the range [20,40].
No influence on the He consumption of the cryomodule.



■ VCR connector for the He cooling circuit:

- In the manufacturing of the tubes, a stress-relief heat treatment is performed at 950°C. For medium beta, the VCR connectors were assembled before heat treatment and at 950°C, the silver coat in the connector begins to flow.
- For medium beta, we were obliged to manually silver coat the connectors of the cryomodule cooling circuit.
- For high beta, we change the sequence of manufacturing, and the VCR connectors are put after the heat treatment



VCR connector of the double-wall tube



VCR connector of the
cryomodule cooling circuit



PREPARATION OF THE COUPLERS BEFORE CONDITIONING (AT CEA)

Window:

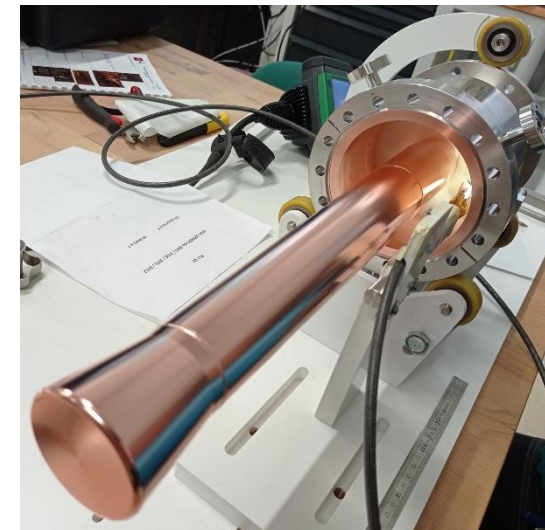
- Windows delivered in a metallic box filled with nitrogen
- Check of the cleanliness
- Visual control of the antenna, inner and outer conductor
- Inspection of seal grooves, knife edge of Conflat flanges
- Inspection of the choke with an endoscope (development of a specific tool)
- Check of the documents

Tube:

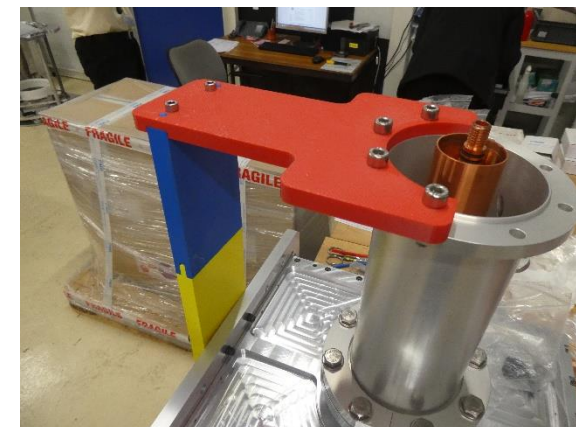
- Tubes delivered in 2 bags under vacuum
- Check of the cleanliness
- Inspection of seal grooves, knife edge of Conflat flanges
- Inspection of the copper layer
- Inspection of the VCR connector and we screw a VCR plug to check the correct screwing
- Check of the documents

Doorknob transition:

- Check of the documents
- Check of the orientation of the flange
- Check of the high voltage insulation after conditioning



Check with endoscope



DK flange orientation

Window:

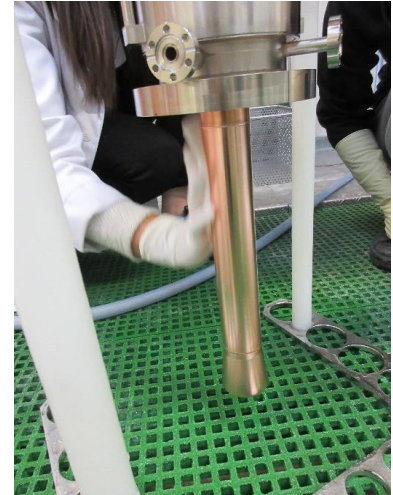
- Manual cleaning with ethanol for window and RBS T310 for the antenna

Tube:

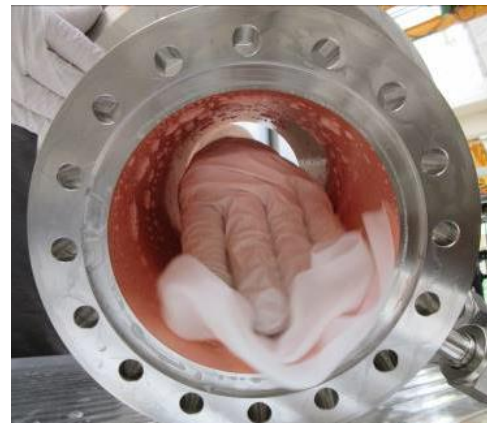
- Ultrasonic bath with the detergent Tickopur R33 (40°C)
- If oxidation marks, manual cleaning with RBS T310

Pick-up electron: Ultrasonic bath with ethanol

Screw: Ultrasonic bath with the detergent Tickopur R33 (50°C)



Manual cleaning with RBS



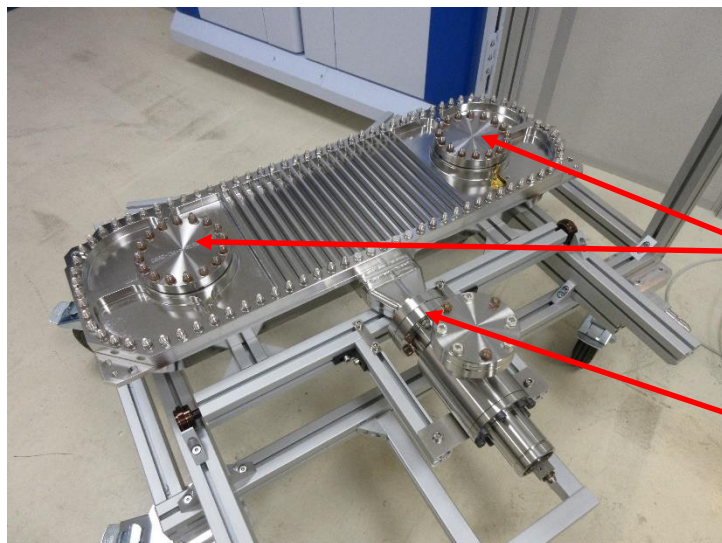
Manual cleaning with RBS



US cleaning with ethanol

US cleaning with Tickopur

- 2 coupler ports + 1 port for a photomultiplier + 1 port for the pumping
- Aluminum wire between top and cover to ensure the vacuum tightness



Coupler ports

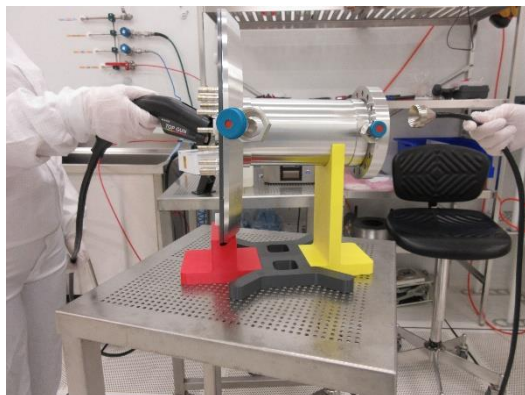
Pumping port



Photomultiplier port



- Particle counting of the tubes, windows
- Assembly of the window on the tube with a robot
- Vacuum tightness test
- Switch on the vacuum gauge to check the correct start-up



Particle counting of the tube



Window on tube



Particle counting of the window

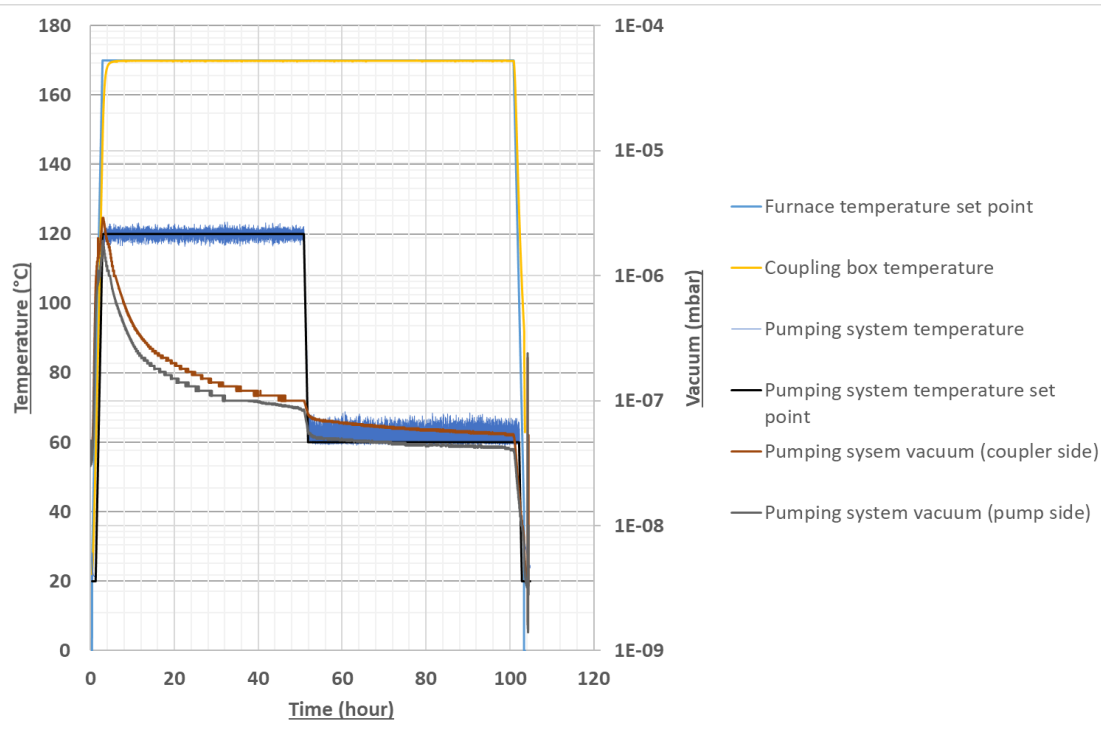


Assembly on the coupling box



Vacuum gauge

- Baking in an oven (couplers 170°C for 4-5 days, pumping system 120°C for 2 days then 60°C)
- Oven filled with nitrogen to limit the oxidation of the copper in the window air side.
- Pumping group is heated with heating tapes
- Residual gas analysis during the baking



Baking (temperature and vacuum)

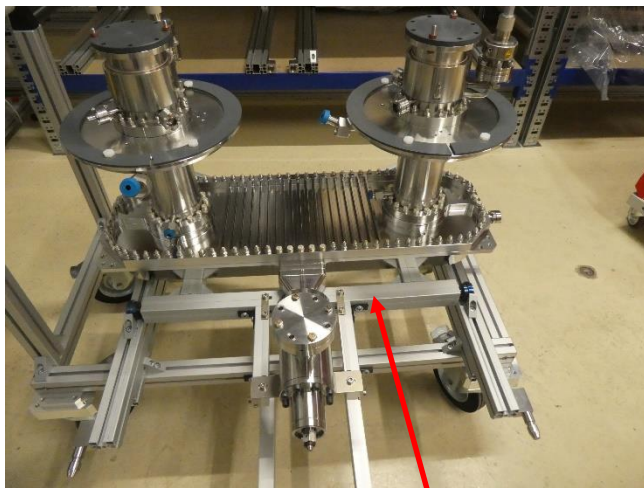


Couplers in the oven

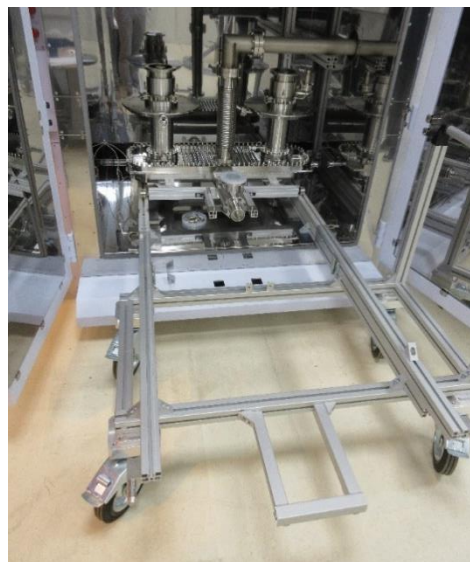


Air side

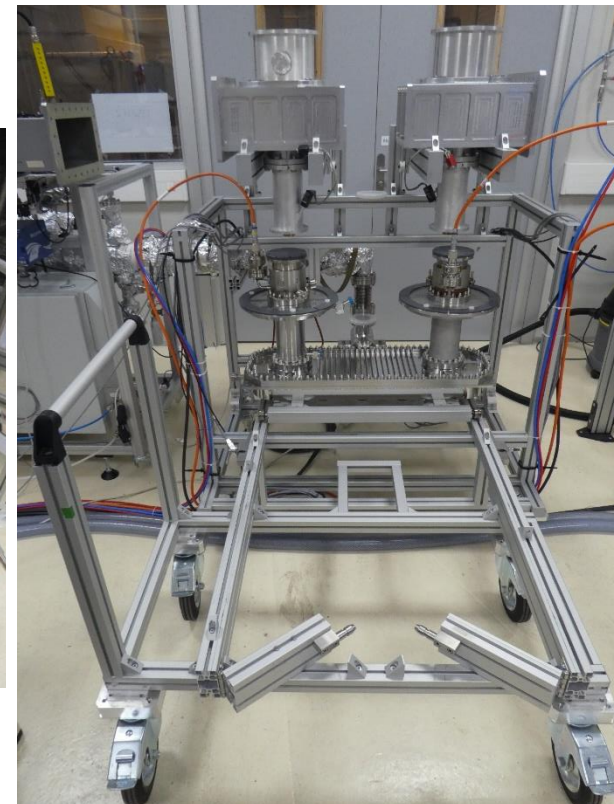
- System of rails to avoid any lifting of the couplers
 - In cleanroom, coupling box put on the trolley
 - Transfer to baking furnace
 - Transfer to conditioning bench



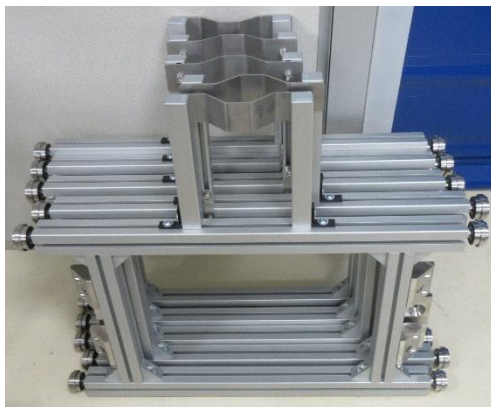
Coupling box on the trolley



Furnace



Conditioning bench



Trolleys



CONDITIONING

- 2 klystrons to perform conditioning of 2 couplers pairs in parallel.
- Couplers conditioned by pair on a coupling box in travelling waves (at 1 Hz then 14Hz) and standing waves (at 1 Hz then 14Hz) for 2 positions of the short circuit (minimum then maximum electric field close to the ceramic).
- Pumping system: effective speed $\approx 20\text{l/s}$, whole conductance $\approx 24\text{l/s}$. Turbo pump: 300l/s .

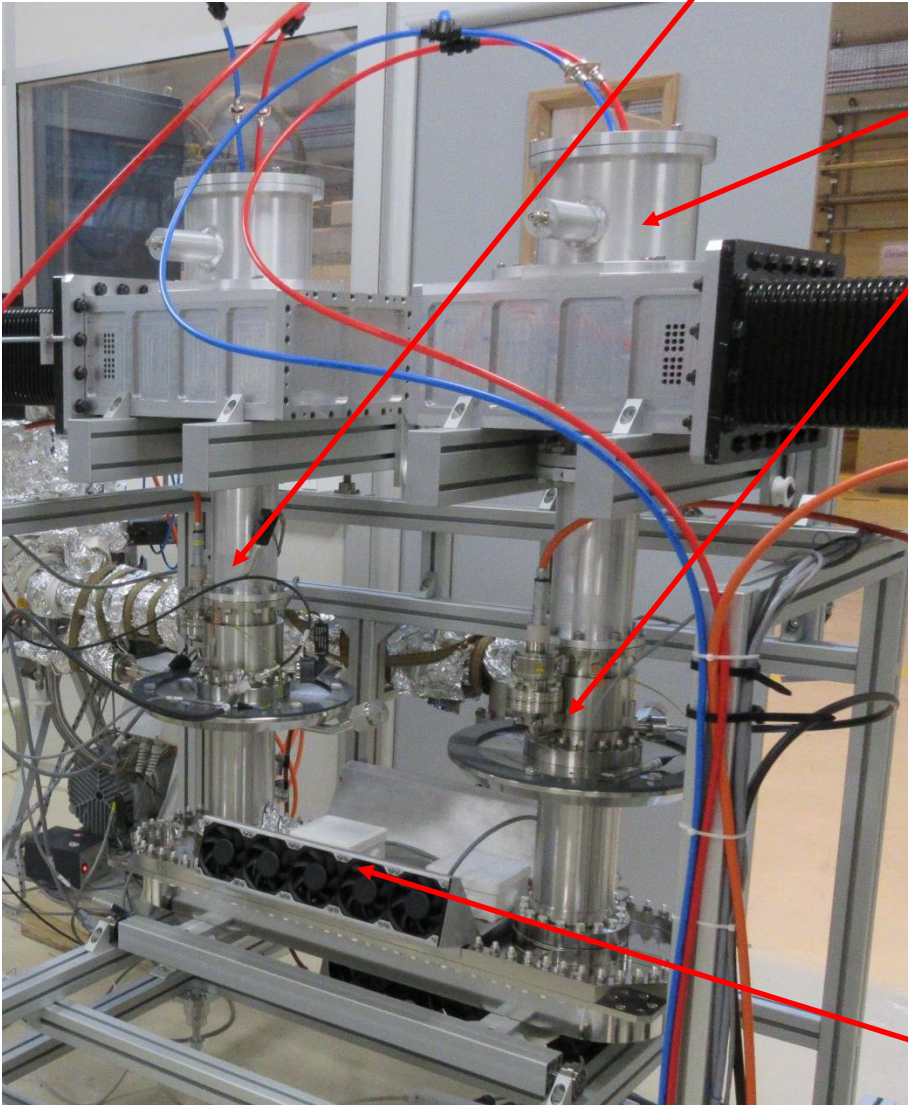


Short circuit
(E min)

Short circuit
(E max)

Load

Zoom on the couplers

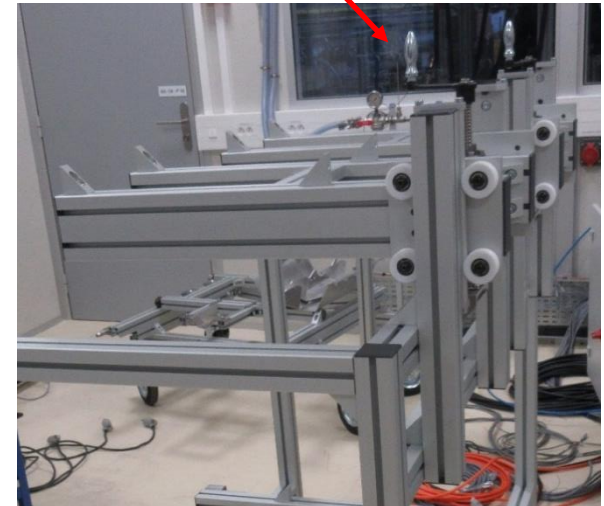


Input coupler

Doorknob transition

Output coupler

Crank handle to put the doorknob



Fans to cool the coupling box



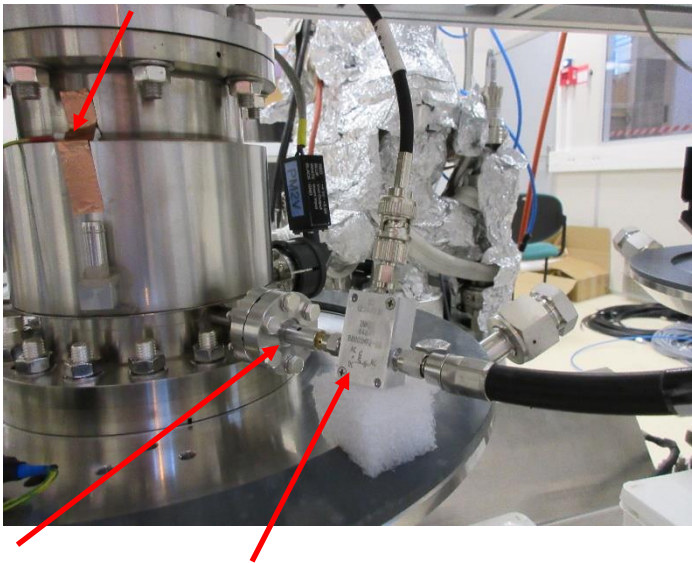
Control instruments on the ESS couplers:

- Vacuum gauge (IKR070 from Pfeiffer)
- Window for photomultiplier (model H10721-110 from HAMAMATSU) (ceramic on the vacuum side)
- Photomultiplier on the doorknob transition (ceramic on the air side)
- Electron pick-up (for multipactor + RF coupling)
- Temperature probe on each window

Control instruments on the coupling box and pumping system:

- Window for photomultiplier on the coupling box
- Vacuum gauges on the pumping system
- Temperature probe on the coupling box

Temperature probe



Pick-up with its bias tee

Photomultiplier (vacuum side)



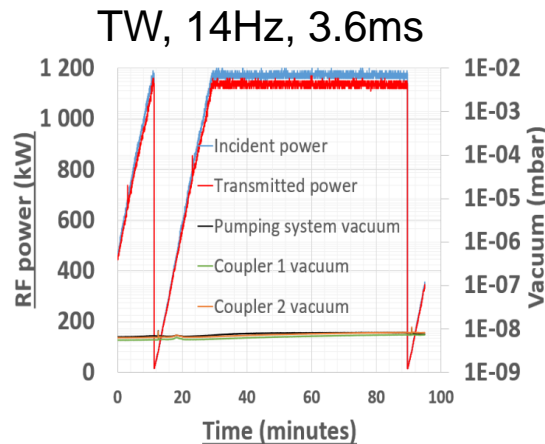
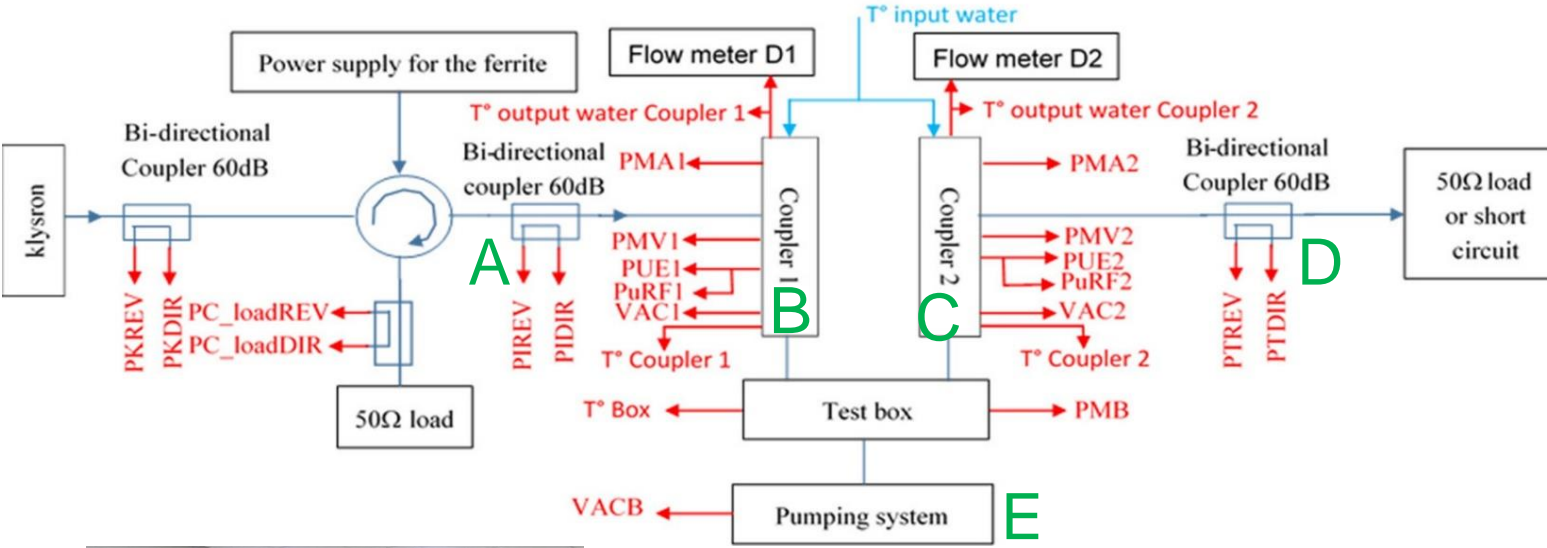
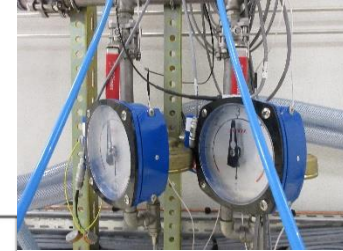
Position of the ceramic disk



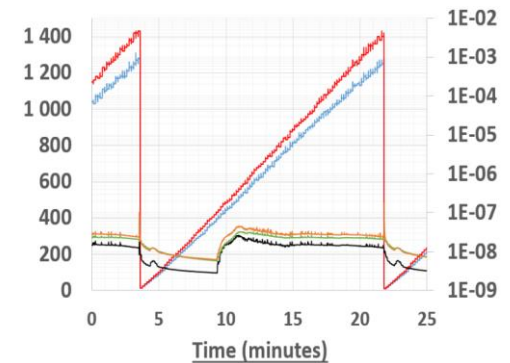
Photomultiplier
(air side)

RF conditioning

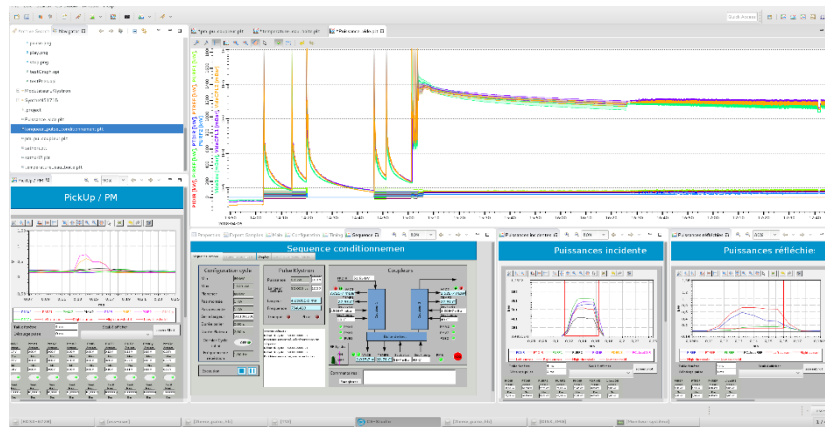
- Check of the incident reverse RF powers, vacuum, electric arcs, multipactor, temperature, water flow



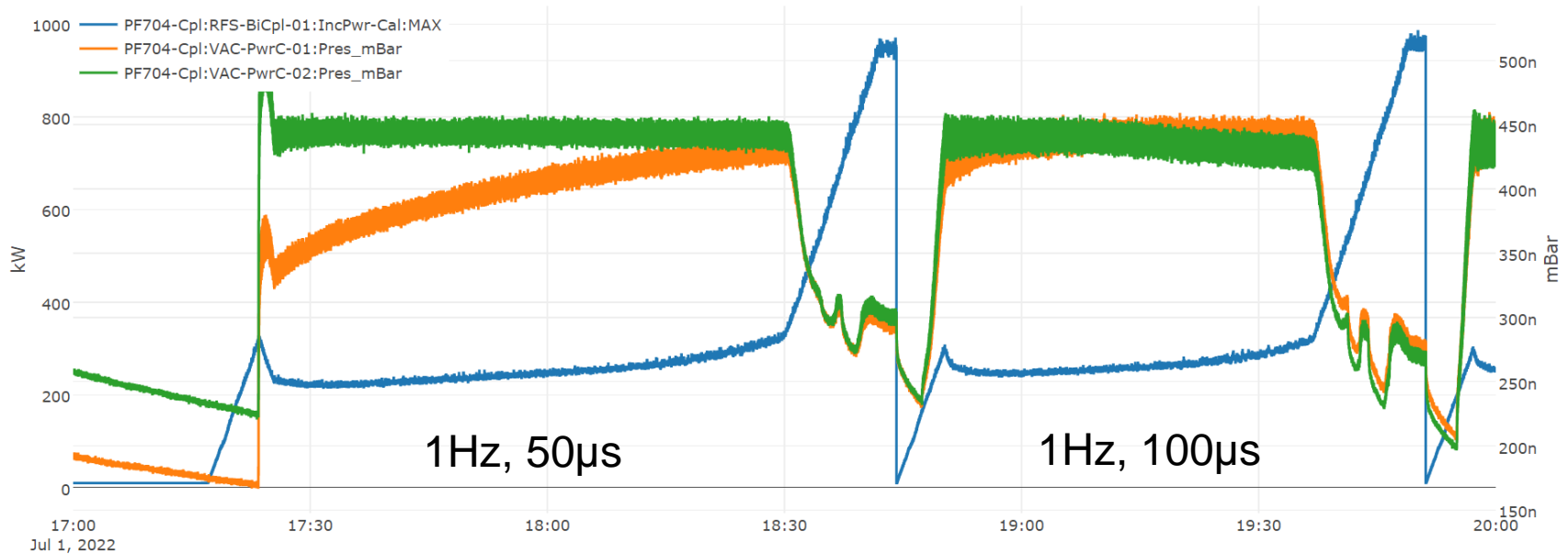
SW, 14Hz, 500μs, Min E



- RF power ramps from around 10 kW to 1.1 MW (pulse width from 50 μ s to 3.6ms), increase step by step (usually 1 kW per second)
- Conditioning mainly on the vacuum (definition of a variable vacuum threshold to increase or decrease the power in function of outgassing)
- RF power switched off when
 - Outgassing with a vacuum level exceeding a hardware threshold defined at 1x10⁻⁶ mbar
 - Presence of electrical arcs whose intensity is greater than around 3 lux (photomultiplier),
 - Presence of electrons whose intensity is greater than 8 mA (detected with the pick-up electron).
 - Temperature of the coupler greater than 45°C or T° of the coupling box greater than 60°C
- The automated handling of all the conditioning sequences, the interlocks and the data recording are controlled with EPICS



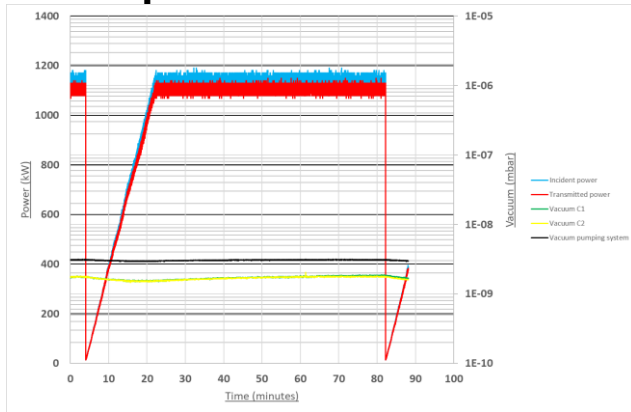
- Beginning of the conditioning: 1Hz, travelling waves. Vacuum threshold fixed at 4.5×10^{-7} mbar



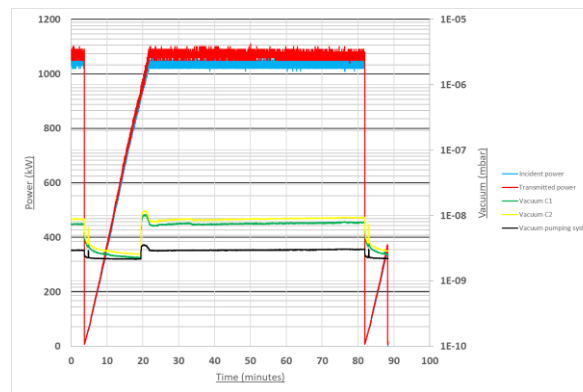
- Acceptance criteria: (defined after the conditioning of 8 prototype couplers)
 - Outgassing lower than 2×10^{-8} mbar
 - TW sequence time lower than 120 RF hours (not really applicable)
 - No parasitic activity (light or electron). RF ramps performed without high voltage bias on the antenna.
- Possibility to apply a HV bias on the antenna: up to 10kV. During conditioning, electron activity rather weak. With a 500V Bias, possibility to reduce activity.

- We have conditioned all the 36 medium beta couplers
- In travelling waves (14Hz, 3.6ms, power ramp+ plateau 1H), 3 kinds of behavior:
 - No outgassing (eg 2025-2026)
 - 1 or 2 outgassing phenomena (at 70kW + around 1040kW or/and at 1.1MW) (eg 2035-2036)
 - “Random” outgassing at 1.1MW (eg 2013-2014)

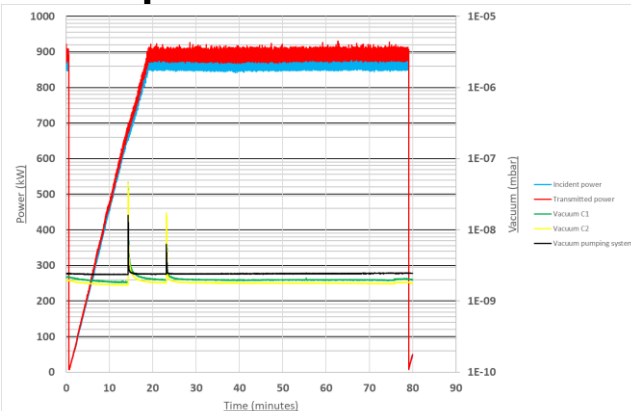
Couplers 2025-2026



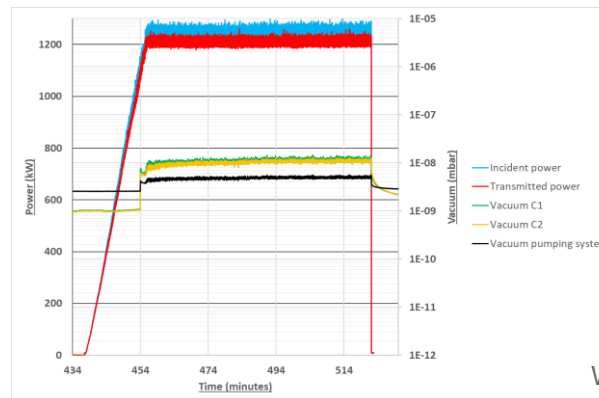
Couplers 2035-2036



Couplers 2013-2014



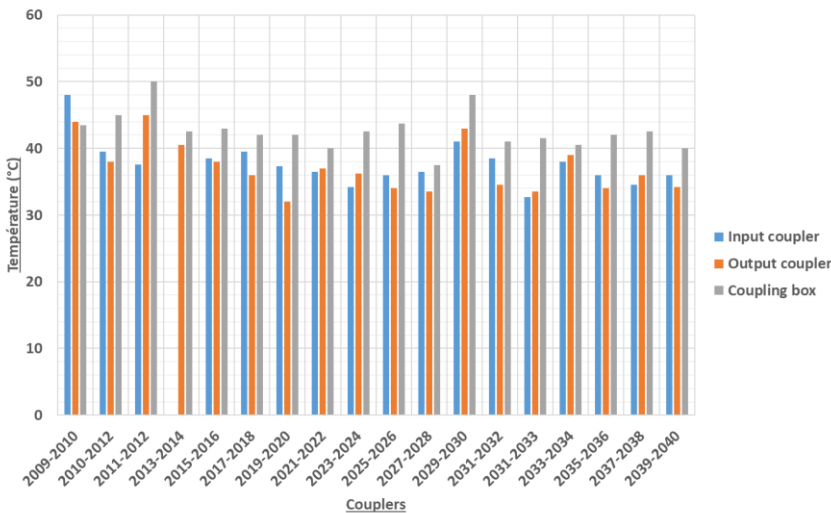
Couplers 2009-2010



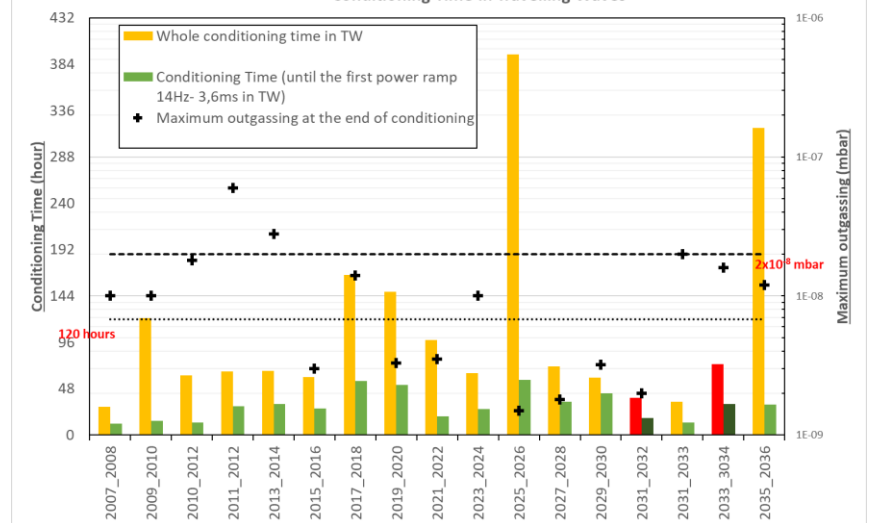
In travelling waves

- Maximum temperature in the range [32°C;45°C] for the maximum average power
- RF time lower than 120H (our defined threshold). On 2 pairs, this time is more important because we wanted to see if we could improve the coupler behavior. Outgassing rather lower than our criterion (2×10^{-8} mbar)

Temperature (TW, 14Hz, 3.6ms, 1.1MW)



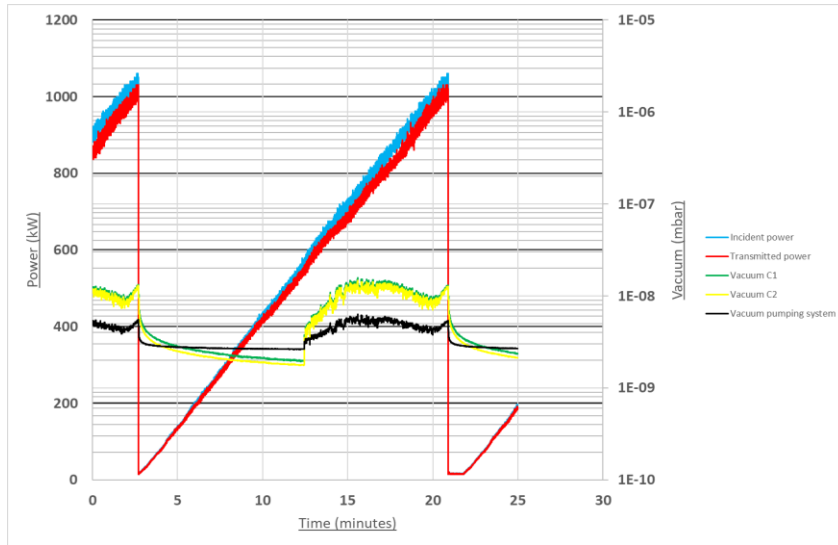
Conditioning Time in Travelling Waves



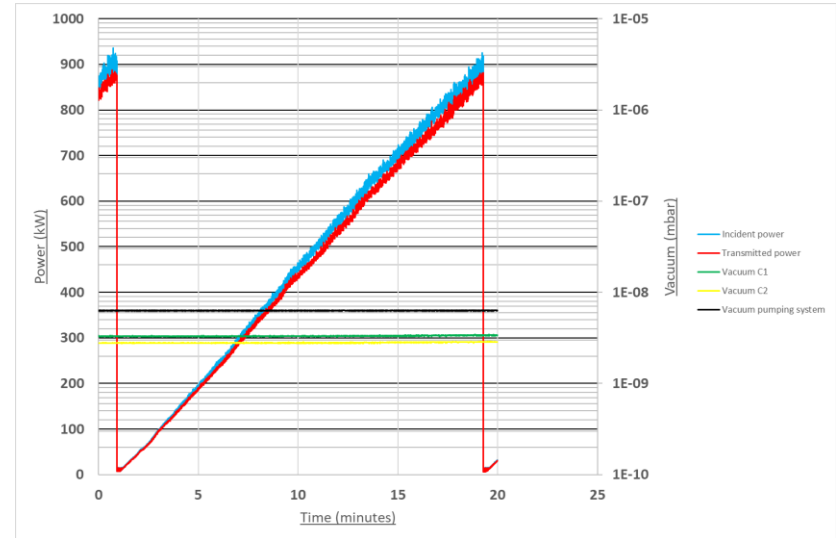
In standing waves

- Position of the short-circuit with maximum electric field close to the ceramic: no parasitic activity
- Position of the short-circuit with minimum electric field close to the ceramic: outgassing lower than our threshold

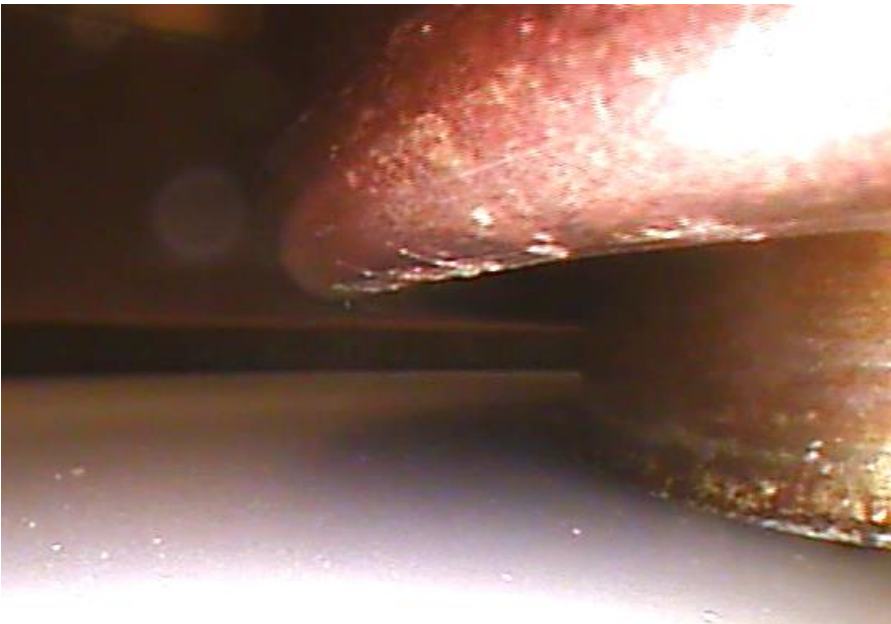
SW min E 14Hz, 500 μ s



SW max E 14Hz, 500 μ s

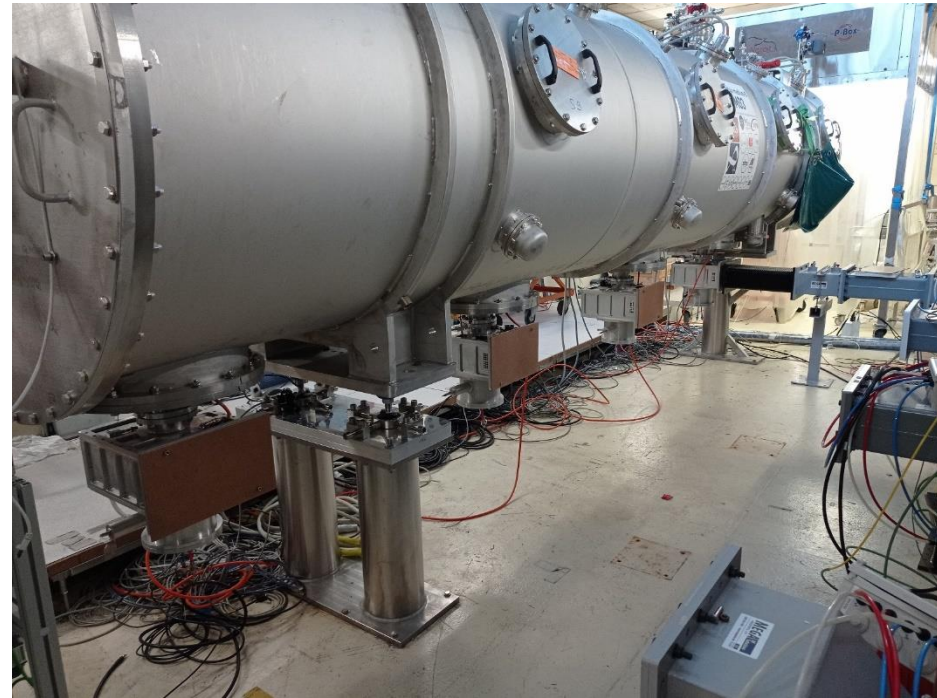


- High Beta couplers (84 couplers to be conditioned): currently, 38 couplers are conditioned. 4 couplers are on the conditioning benches.
- During the medium and high beta couplers conditioning (36+38=74 couplers), we have rejected
 - 11 windows: 6 windows due to a bad TiN coating (high temperature in the window), 5 windows because of electrical arcs (after inspection, we saw that the chokes were damaged).
 - 1 tube due to a scratch



- Successful conditioning of 74 medium and high beta couplers (46 couplers have to be conditioned).
- Manufacturing:
 - The most critical aspect is the Tin coating quality
 - Copper coating is operator dependent (slight default)
- Conditioning mainly on the vacuum. We try to have no activity (no electrical arcs and electron). We accept an outgassing lower than 2×10^{-8} mbar (pumping speed ≈ 20 l/s)
- 6 cryomodules tested in CEA or ESS and accepted
 - Conditioning at ambient temperature (Standing waves)
 - Conditioning at nominal temperature (flange cavity: 2K) (Standing waves)
 - Nominal field in the cavities: MB 16.7MV/m and HB 19.9 MV/m
 - On the cryomodules, the short circuit position is different from the two positions tested during the couplers conditioning
 - Electron activity can be conditioned rather quickly (≈ 5 hours)

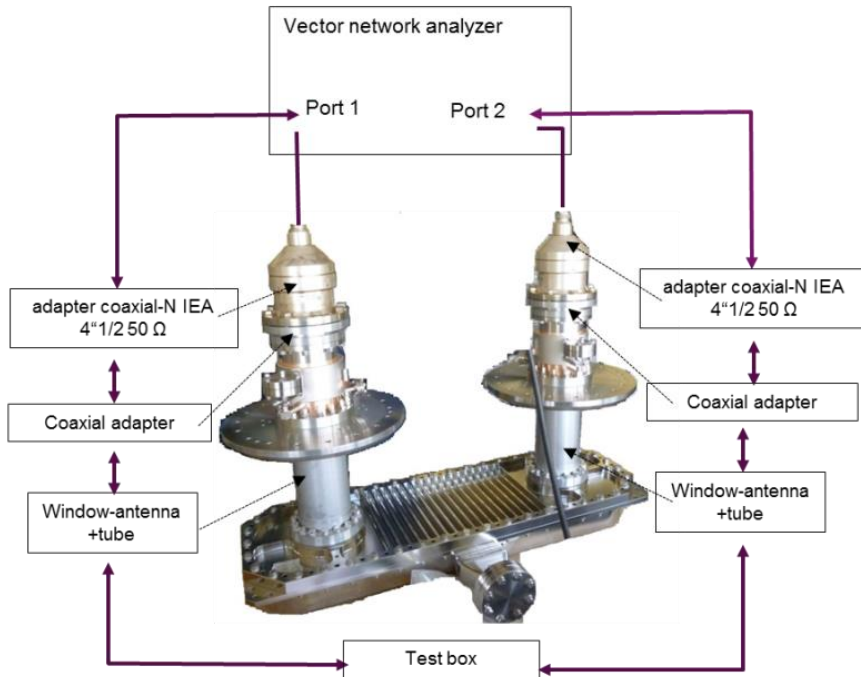
Thanks for your attention



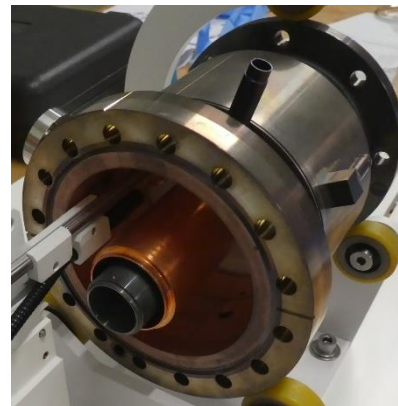
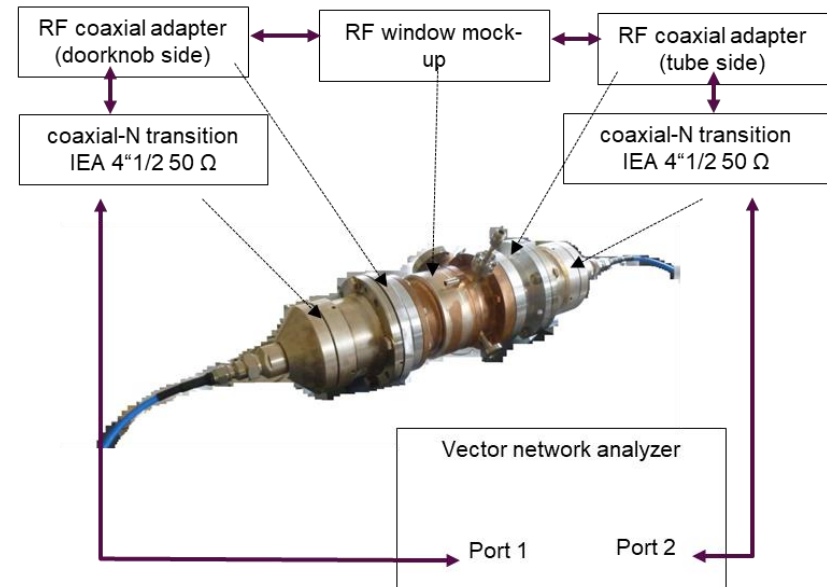


APPENDICES

2 couplers on a coupling box



Window without antenna

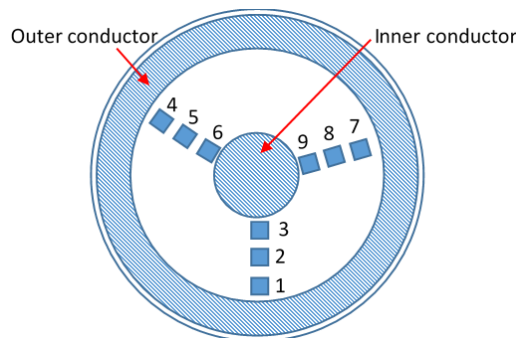


Window mock-up without antenna

To check the compliance of the TiN coating, Stoichiometric (XPS method, X-ray photoelectron spectroscopy) and thickness measurements (Secondary Ion Mass Spectrometry-SIMS method) on

- 1 vitreous carbon sample put on the cavity flange for each window
- 8 vitreous carbon samples put on the ceramic in a window mock-up

N° Sample	Ti (%)	N (%)	O (%)
2	42.2	31.7	24.5
5	41.7	37	19.6
8	42.2	32.3	24
10	42.7	41.6	15.7



Sample from window	Ti (%)	N (%)	O (%)	C(%)
2011	16.5	13.8	22.7	46.4
2014	19.9	18.2	25.1	36.5
2016	19.4	17.3	25.1	37.6
2018	18.8	17.1	23.5	40.0
2021	20.0	17.1	26.9	35.5
2025	18.8	17.4	24.9	37.9

Pre-series (1st TiN subcontractor)

Series (2nd sub-contractor)

■ Stoichiometric measurement on vitreous carbon samples on the flanges of the series couplers: Ti present in TiO₂, TiO_xN_y and TiN form

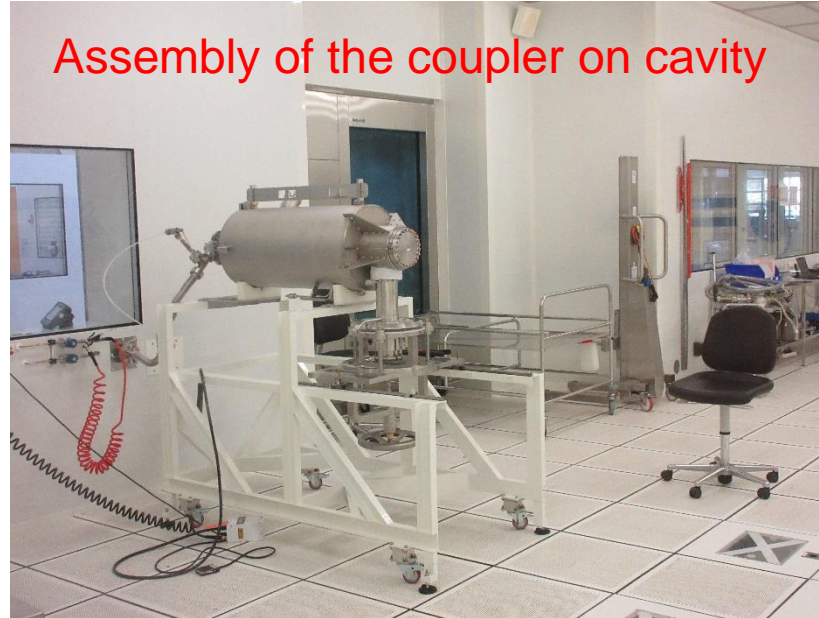
■ Measurement of the dielectric properties of a ceramic with the new TiN coating

- $\epsilon_r=9.46$, $\tan \delta=2.65 \times 10^{-4}$
- a ceramic without TiN ($\epsilon_r=9.47$ and $\tan \delta= 2.78 \times 10^{-4}$)

- Transfer of couplers to industrial partner for the assembly of couplers on cavity



Train of 4 cavities



Assembly of the coupler on cavity

- Difficulties to obtain vacuum tightness on some interfaces

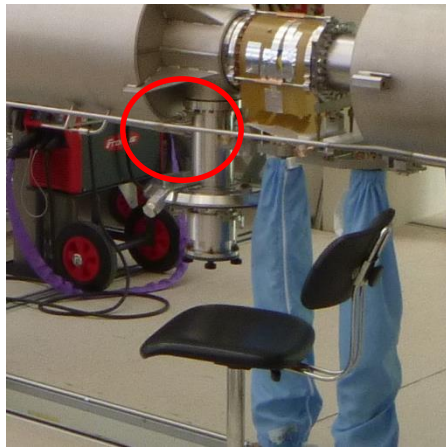
- VCR connector
- Coupler bellow bell



Bellow bell



Sealing surface



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